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Joint ICTP-IAEA Workshop on Physics of Radiation Effect and its Simulation for Non-Metallic Condensed Matter | (smr 2359)

Friday 17 August 2012

Ion Beam Lithography I. - Adriatico Guest House Kastler Lecture Hall (11:00-12:30)

The basic concepts on the employment of keV and MeV ions for the micro- and nano-fabrication of advanced materials will be introduced, with comparisons with standard lithographic techniques. The current state of the art on most significant applications of ion beam lithography in materials of widespread use (such as silicon and photo-resists) will be reviewed.

time	title	presenter
11:00	Ion Beam Lithography I.	PAOLO OLIVERO